

Title (en)

FOREIGN MATTER REMOVING DEVICE FOR USE IN TURNOUT

Title (de)

VORRICHTUNG ZUM ENTFERNEN VON FREMDSTOFFEN ZUR VERWENDUNG IN WEICHEN

Title (fr)

DISPOSITIF D'ÉLIMINATION DE MATIÈRES ÉTRANGÈRES DESTINÉ À ÊTRE UTILISÉ DANS UN BRANCHEMENT

Publication

**EP 3434824 A1 20190130 (EN)**

Application

**EP 18192212 A 20151112**

Priority

- EP 18192212 A 20151112
- EP 15194184 A 20151112

Abstract (en)

The present invention relates to a foreign matter removing device for use in a turnout comprising an inlet member including an inlet channel for introducing a foreign matter removable medium, the inlet member extending in a width direction of the base rail in a region lower than a bottom surface of the base rail; and a connecting portion including a communication channel for communicating a nozzle portion which injects the foreign matter removable medium to between the base rail and the tongue rail, and the inlet channel, wherein the connecting portion is connected to one end portion of the inlet member in the region lower than the bottom surface of the base rail, view such that an operator is allowed to connect the one end portion of the inlet member to the connecting portion, and the connecting portion includes an opposing portion which faces the first leg portion in a width direction of the base rail, a holding plate to be mounted on the second leg portion; and a pulling member to be hooked onto the inlet member, and to exert a pulling force on the Inlet member in such a manner that the opposing portion is pressed against the first leg portion, utilizing a counterforce of the holding plate, and the holding plate holds the pulling member in such a manner that a relative position of the pulling member with respect to the inlet member is changeable in the width direction of the base rail.

IPC 8 full level

**E01B 7/20** (2006.01); **E01B 19/00** (2006.01)

CPC (source: EP)

**E01B 7/20** (2013.01); **E01B 19/00** (2013.01)

Citation (applicant)

- WO 2013038657 A1 20130321 - HIGASHI NIPPON RYOKAKU TETSUDO [JP], et al
- JP 2000144602 A 20000526 - NABCO LTD, et al

Citation (search report)

- [AD] JP 2000144602 A 20000526 - NABCO LTD, et al
- [AD] WO 2013038657 A1 20130321 - HIGASHI NIPPON RYOKAKU TETSUDO [JP], et al
- [A] CA 1213966 A 19861112 - IEC HOLDEN INC
- [A] US 6065721 A 20000523 - SUMPTON DANNY M [CA], et al

Designated contracting state (EPC)

AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

DOCDB simple family (publication)

**EP 3168365 A1 20170517**; EP 3434824 A1 20190130

DOCDB simple family (application)

**EP 15194184 A 20151112**; EP 18192212 A 20151112